

WS-1000MH Mini Station



Engineered

An advanced coating, etching, developing, or cleaning system, mounted in a work station, designed and built for you and your process.

Capable

Can be configured with systems for processing wafers up to 300 mm.

Optional Touch Interface for the most powerful and flexible control system available.

Safe

Chemical containment, leak detection, sensors, interlocks, and alarms provide essential protection for the operator.



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WS-1000 Full Station



Laurell Technologies has 28 years of experience with our customers' complex processes, multiple chemistries, safety issues, waste containment, and disposal issues.

Benefit from our expertise and let us engineer your convenient solution.

WS-1000 Full Station

EDC-650-8NPP & EDC-650-8TFM

With Optional Touch Screen Interface

Options and Accessories

Touch Screen Interface: Control, program and monitor all operations with a touch.

Bluetooth® Wireless Technology

Rinse to Resistivity: Detects rinse completion and alerts the processor to dry the substrate, saving valuable resources usually wasted on a time-based system.

Multi-Position Non-Contact Level Sensing: Either in a drain reservoir or supply container - fully programmable.

Leak Detection: Laurell uses the most dependable sensor technology available - audible and visual alarms with industry-standard light tree.

Heated Process Chemistry: with point-of-use or recirculation type heat exchangers.

Teflon® Spin Housing: We only use **semiconductor grade Teflon®** with **zero porosity** to prevent "chemical memory" effects (processor shown on right above).

Teflon® is a registered trademark of E. I. du Pont de Nemours & Co.

